

07-26-02

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Express Mail No.: EL 451 597 892 US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of: Steven M. Chase, Connie J. Chang-Hasnain and Jeffrey M. Waite

Application No.: 09/693,612

Group Art Unit: 2872

Filed: October 20, 2000

Examiner: Ricky D. Shafer

For:

Apparatus and Method for
Controlled Cantilever
Motion Through Torsional
Beams and a Counterweight

Attorney Docket No.: 9840-0053-999

Date: July 24, 2002

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AMENDMENT AND RESPONSE TO OFFICE ACTION

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Enclosed is an amendment responsive to the Office Action dated June 28, 2002, for the above identified patent application.

- ☒ The Commissioner is hereby authorized to charge all fees that may be required, to Deposit Account No. 16-1150 (Order No. 9840-0053-999).
A copy of this page is enclosed.

Respectfully submitted,

Date:

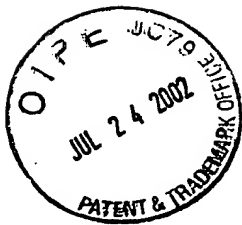
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of: Steven M. Chase, Connie J. Chang-Hasnain and Jeffrey M. Waite

#13k (W)
JMM
8202

Application No.: 09/693,612

Group Art Unit: 2872

Filed: October 20, 2000

Examiner: Ricky D. Shafer

For: Apparatus and Method for Controlled Cantilever Motion Through Torsional Beams and a Counterweight Attorney Docket No.: 9840-0053-999 Date: July 24, 2002

AMENDMENT AND RESPONSE TO OFFICE ACTION

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

This communication is responsive to the Office Action dated June 28, 2002, for the above identified patent application. A response is due September 28, 2002. Please amend the application as follows.

IN THE CLAIMS:

Cancel claim 28.

Claims 8-11 and 16-19 were withdrawn by the Examiner.

Revisions to the claims are shown in Appendix A.

Rewrite the pending claims as follows:

1. (amended) An optical micro-electromechanical device, comprising:
a substrate; and
a mirror assembly suspended above said substrate, said substrate and said mirror together forming a Fabry-Perot cavity, said mirror assembly including:
a torsional beam attached to said substrate,

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